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EE C247B - ME C218 Introduction to MEMS Design Spring 2016

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Lecture Module 2: Benefits of Scaling

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Basic Concept: Scaling Guitar Strings

Guitar String

Vibrating "A" String (110 Hz)

Stiffness

Freq. Equation:

$$f_o = \frac{1}{2\pi} \sqrt{\frac{k_r}{m_r}}$$

Mass

μMechanical Resonator

[Bannon 1996]

Performance:

- $L_r = 40.8 \mu\text{m}$
- $m_r \sim 10^{-13} \text{ kg}$
- $W_r = 8 \mu\text{m}, h_r = 2 \mu\text{m}$
- $d = 1000 \text{ \AA}, V_p = 5 \text{ V}$
- Press. = 70 mTorr

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3CC 3λ/4 Bridged μMechanical Filter

Performance:

- $f_o = 9 \text{ MHz}, BW = 20 \text{ kHz}, PBW = 0.2\%$
- $I.L. = 2.79 \text{ dB}, \text{Stop. Rej.} = 51 \text{ dB}$
- $20 \text{ dB S.F.} = 1.95, 40 \text{ dB S.F.} = 6.45$

Design:

- $L_r = 40 \mu\text{m}$
- $W_r = 6.5 \mu\text{m}$
- $h_r = 2 \mu\text{m}$
- $L_c = 3.5 \mu\text{m}$
- $L_p = 1.6 \mu\text{m}$
- $V_p = 10.47 \text{ V}$
- $P = -5 \text{ dBm}$
- $R_{Qi} = R_{Qo} = 12 \text{ k}\Omega$

[S.-S. Li, Nguyen, FCS'05]

[Li, et al., UFFCS'04]

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Micromechanical Filter Circuit

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1.51-GHz, Q=11,555 Nanocrystalline Diamond Disk μ Mechanical Resonator

- Impedance-mismatched stem for reduced anchor dissipation
- Operated in the 2nd radial-contour mode
- Q ~11,555 (vacuum); Q ~10,100 (air)
- Below: 20 μ m diameter disk

Design/Performance:
 $R=10\mu\text{m}$, $t=2.2\mu\text{m}$, $d=800\text{\AA}$, $V_p=7\text{V}$
 $f_o=1.51\text{ GHz}$ (2nd mode), $Q=11,555$

EE C245: Introduction to MEMS Design LecM 2 [Wang, Butler, Nguyen MEMS'04]

163-MHz Differential Disk-Array Filter

EE C245: Introduction to MEMS Design [Li, Nguyen Trans'07]

Linear MEMS in Wireless Comms

High Q and good linearity of micromechanical resonators → Filters for front-end frequency selection

Micromechanical Bandpass Filter

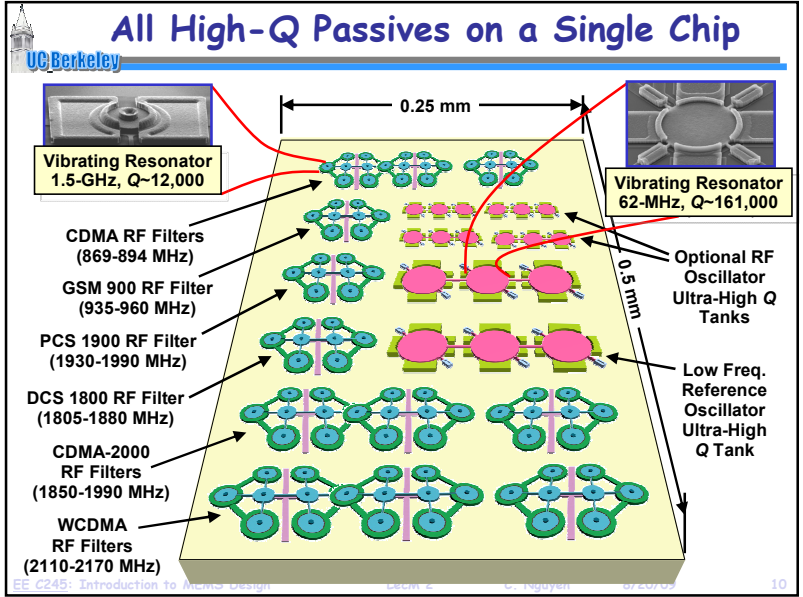
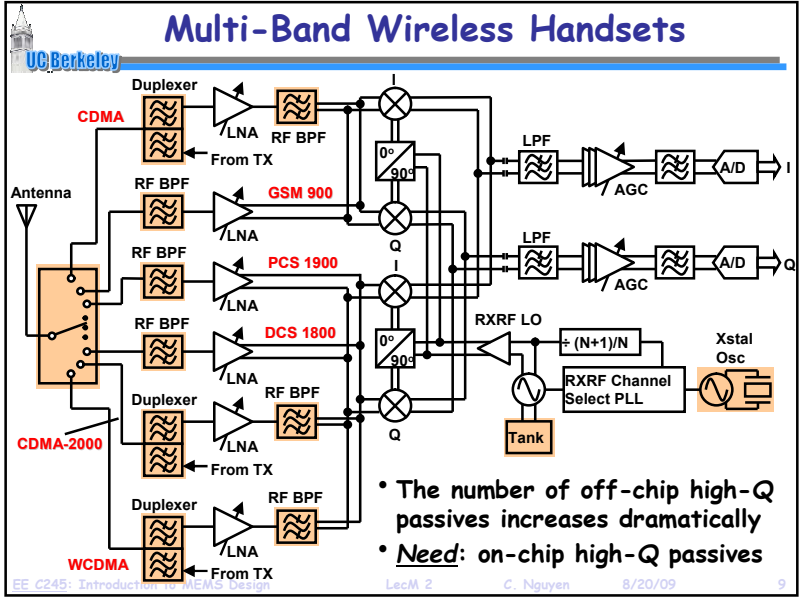
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Miniaturization of RF Front Ends

- RF Power Amplifier
- 897.5±17.5MHz RF SAW Filter
- Dual-Band Zero-IF Transistor Chip
- 3420-3840MHz VCO
- Diplexer
- 925-960MHz RF SAW Filter
- 1805-1880MHz RF SAW Filter
- 26-MHz Xstal Oscillator

Problem: high-Q passives pose a bottleneck against miniaturization

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Chip-Scale Atomic Clocks (CSAC)

NIST F1 Fountain Atomic Clock

Vol: ~3.7 m³
Power: ~500 W
Acc: 1×10^{-15}
Stab: 3.3×10^{-15} /hr

After 1 sec ⇨
Error: 10^{-15} sec

↓

Loses 1 sec every 30 million years!

Physics Package

Benefits of Accurate Portable Timing

Better Timing

Secure Communications

- More efficient spectrum utilization
- Longer autonomy periods
- Faster frequency hop rates
- Faster acquire of pseudorandom signals
- Superior resilience against jamming or interception

Networked Sensors

- Larger networks with longer autonomy

GPS

- Fewer satellites needed
- Higher jamming margin
- Faster GPS acquire

NIST F1 Fountain Atomic Clock

Vol: ~3.7 m³
Power: ~500 W
Acc: 1 × 10⁻¹⁵
Stab: 3.3 × 10⁻¹⁵/hr

After 1 sec ⇒ **Error: 10⁻¹⁵ sec**

Loses 1 sec every 30 million years!

Physics Package

1st Chip-Scale Atomic Physics Package

Total Volume: 9.5 mm³
Cell Interior Vol: 0.6 mm³
Stability: 2.4 × 10⁻¹⁰ @ 1s
Power Cons: 75 mW

ND, Quartz, Si, ND, Glass, Alumina, VCSEL, Lens, Laser, Optics, Cell, Photodiode

Tiny Physics Package Performance

Experimental Conditions:

- Cs D2 Excitation
- External (large) Magnetic Shielding
- External Electronics & LO
- Cell Temperature: ~80 °C
- Cell Heater Power: 69 mW
- Laser Current/Voltage: 2mA / 2V
- RF Laser Mod Power: 70µW

Stability Measurement:

Open Loop Resonance:

Sufficient to meet CSAC program goals

Atomic Clock Fundamentals

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- Frequency determined by an atomic transition energy

Energy Band Diagram

Excite e- to the next orbital

Opposite e- spins

$\Delta E = 1.46 \text{ eV}$
 $\nu = \Delta E/h = 352 \text{ THz}$
 $\Rightarrow 852.11 \text{ nm}$

$\Delta E = 0.000038 \text{ eV}$
 $\nu = \Delta E/h = 9\,192\,631\,770 \text{ Hz}$

$m = 1$
 $m = 0$
 $f = 4$
 $f = 3$

^{133}Cs

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Miniature Atomic Clock Design

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Carrier (852 nm)

Sidebands

4.6GHz

9.2GHz

Atoms become transparent to light at 852 nm

$\nu = \Delta E/h = 9\,192\,631\,770 \text{ Hz}$

Hyperfine Splitting Freq.

Modulated Laser

^{133}Cs vapor at 10^{-7} torr

Photo Detector

Mod f

Close feedback loop to lock

VCXO

$\mu\text{wave osc}$

4.6 GHz

ν_o

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Chip-Scale Atomic Clock

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Laser

^{133}Cs vapor at 10^{-7} torr

Mod f

Photo Detector

VCSEL

Cs or Rb

Glass

Detector

Substrate

GHz Resonator in Vacuum

VCXO

$\mu\text{wave osc}$

4.6 GHz

ν_o

Atomic Clock Concept

MEMS and Photonic Technologies

Key Challenges:

- thermal isolation for low power
- cell design for maximum Q
- low power $\mu\text{wave oscillator}$

Chip-Scale Atomic Clock

Vol: 1 cm^3
 Power: 30 mW
 Stab: 1×10^{-11}

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Challenge: Miniature Atomic Cell

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Large Vapor Cell

Tiny Vapor Cell

1,000X Volume Scaling

Surface Volume \uparrow

More wall collisions \Rightarrow stability gets worse

Atomic Resonance

Intensity

Mod f

lowest Q

lower Q

9.2 GHz

Wall collision dephases atoms \Rightarrow lose coherent state

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Challenge: Miniature Atomic Cell

Large Vapor Cell

Tiny Vapor Cell

1,000X Volume Scaling

Soln: Add a buffer gas → Lower the mean free path of the atomic vapor

9.2 GHz

Chip-Scale Atomic Clock

Atomic Clock Concept

4.6 GHz

VCXO μ wave osc

Mod f

Photo Detector

MEMS and Photonic Technologies

VCSEL
Cs or Rb
Glass
Detector
Substrate

Key Challenges:

- thermal isolation for low power
- cell design for maximum Q
- low power μ wave oscillator

Chip-Scale Atomic Clock

Vol: 1 cm³
 Power: 30 mW
 Stab: 1x10⁻¹¹

Micro-Scale Oven-Control Advantages

Macro-Scale

Atomic Cell @ 80°C

3 cm

Macro-Oven (containing heater and T sensor)

Insulation

Laser

Thermally Isolating Feet

$R_{th} = 38 \text{ K/W}$
 $C_{th} = 22 \text{ J/K}$

$P (@ 80^\circ\text{C}) = 1.5 \text{ W}$

Warm Up, $\tau = 16 \text{ min.}$

Micro-Scale

300x300x300 μm^3 Atomic Cell @ 80°C

Heater

Laser

Long, Thin Polysilicon Tethers

T Sensor (underneath)

$R_{th} = 83,000 \text{ K/W}$
 $C_{th} = 6.3 \times 10^{-6} \text{ J/K}$

$P (@ 80^\circ\text{C}) = 2.6 \text{ mW}$

Warm Up, $\tau = 0.1 \text{ s}$

$T = P \times R_{th}$

$R_{th} \sim \frac{\text{support length}}{\text{X-section area}}$

$C_{th} \sim \text{volume}$

550x lower power

7,300x faster warm up

Physics Package Power Diss. < 10 mW

• Achieved via MEMS-based thermal isolation

Cesium cell

VCSEL / Photodiode

Heater/Sensor Suspension

Frame Spacer

VCSEL Suspension

Symmetricom / Draper Physics Package Assembly

20 pin LCC

7 mm

Only ~5 mW heating power needed to achieve 80°C cell temperature

Power [mW]

Temperature [°C]

Measured (blue diamonds), Model (red line)